# Kenichiro Mizohata

#### List of Publications by Citations

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103 1,337 29 22 h-index g-index citations papers 108 1,647 4.63 5.2 avg, IF L-index ext. citations ext. papers

#	Paper	IF	Citations
103	Atomic Layer Deposition of Crystalline MoS2 Thin Films: New Molybdenum Precursor for Low-Temperature Film Growth. <i>Advanced Materials Interfaces</i> , <b>2017</b> , 4, 1700123	4.6	<i>75</i>
102	Atomic layer deposition of Ge2Sb2Te5 thin films. <i>Microelectronic Engineering</i> , <b>2009</b> , 86, 1946-1949	2.5	58
101	Atomic Layer Deposition of Rhenium Disulfide. <i>Advanced Materials</i> , <b>2018</b> , 30, e1703622	24	45
100	Atomic Layer Deposition of Antimony and its Compounds Using Dechlorosilylation Reactions of Tris(triethylsilyl)antimony. <i>Chemistry of Materials</i> , <b>2011</b> , 23, 247-254	9.6	40
99	Atomic Layer Deposition of Emerging 2D Semiconductors, HfS2 and ZrS2, for Optoelectronics. <i>Chemistry of Materials</i> , <b>2019</b> , 31, 5713-5724	9.6	36
98	A pyrazolate-based metalorganic tantalum precursor that exhibits high thermal stability and its use in the atomic layer deposition of ta(2)o(5). <i>Journal of the American Chemical Society</i> , <b>2007</b> , 129, 12370-1	16.4	36
97	Atomic Layer Deposition of PbI2 Thin Films. <i>Chemistry of Materials</i> , <b>2019</b> , 31, 1101-1109	9.6	34
96	Low-Temperature Atomic Layer Deposition of Cobalt Oxide as an Effective Catalyst for Photoelectrochemical Water-Splitting Devices. <i>Chemistry of Materials</i> , <b>2017</b> , 29, 5796-5805	9.6	32
95	Influence of microstructure on temperature-induced ageing mechanisms of different solar absorber coatings. <i>Solar Energy Materials and Solar Cells</i> , <b>2014</b> , 120, 462-472	6.4	31
94	Rare earth scandate thin films by atomic layer deposition: effect of the rare earth cation size. Journal of Materials Chemistry, <b>2010</b> , 20, 4207		29
93	Radiation resistance diagnostics of wide-gap optical materials. <i>Optical Materials</i> , <b>2016</b> , 55, 164-167	3.3	28
92	Atomic Layer Deposition of AlF3 Thin Films Using Halide Precursors. <i>Chemistry of Materials</i> , <b>2015</b> , 27, 604-611	9.6	27
91	Direct observation of mono-vacancy and self-interstitial recovery in tungsten. <i>APL Materials</i> , <b>2019</b> , 7, 021103	5.7	25
90	Electric and Magnetic Properties of ALD-Grown BiFeO3 Films. <i>Journal of Physical Chemistry C</i> , <b>2016</b> , 120, 7313-7322	3.8	25
89	Thermal Atomic Layer Deposition of Continuous and Highly Conducting Gold Thin Films. <i>Chemistry of Materials</i> , <b>2017</b> , 29, 6130-6136	9.6	25
88	Nucleation and Conformality of Iridium and Iridium Oxide Thin Films Grown by Atomic Layer Deposition. <i>Langmuir</i> , <b>2016</b> , 32, 10559-10569	4	24
87	Studies on Thermal Atomic Layer Deposition of Silver Thin Films. <i>Chemistry of Materials</i> , <b>2017</b> , 29, 2040-	-29045	23

### (2018-2015)

86	Atomic layer deposition and characterization of Billelthin films. <i>Journal of Physical Chemistry A</i> , <b>2015</b> , 119, 2298-306	2.8	23	
85	Heteroleptic Cyclopentadienyl-Amidinate Precursors for Atomic Layer Deposition (ALD) of Y, Pr, Gd, and Dy Oxide Thin Films. <i>Chemistry of Materials</i> , <b>2016</b> , 28, 5440-5449	9.6	23	
84	Atomic Layer Deposition of Iridium Thin Films Using Sequential Oxygen and Hydrogen Pulses. Journal of Physical Chemistry C, <b>2016</b> , 120, 15235-15243	3.8	23	
83	Thermal diffusivity degradation and point defect density in self-ion implanted tungsten. <i>Acta Materialia</i> , <b>2020</b> , 193, 270-279	8.4	22	
82	Cycloheptatrienyl-Cyclopentadienyl Heteroleptic Precursors for Atomic Layer Deposition of Group 4 Oxide Thin Films. <i>Chemistry of Materials</i> , <b>2012</b> , 24, 2002-2008	9.6	22	
81	Atomic layer deposition of crystalline molybdenum oxide thin films and phase control by post-deposition annealing. <i>Materials Today Chemistry</i> , <b>2018</b> , 9, 17-27	6.2	22	
80	Atomic layer deposition and properties of mixed Ta2O5 and ZrO2 films. <i>AIP Advances</i> , <b>2017</b> , 7, 025001	1.5	21	
79	Diamine Adduct of Cobalt(II) Chloride as a Precursor for Atomic Layer Deposition of Stoichiometric Cobalt(II) Oxide and Reduction Thereof to Cobalt Metal Thin Films. <i>Chemistry of Materials</i> , <b>2018</b> , 30, 349	9 <del>9:</del> §50	7 <sup>21</sup>	
78	Magnetic Properties of Polycrystalline Bismuth Ferrite Thin Films Grown by Atomic Layer Deposition. <i>Journal of Physical Chemistry Letters</i> , <b>2014</b> , 5, 4319-23	6.4	21	
77	Atomic Layer Deposition of Photoconductive CuO Thin Films. ACS Omega, 2019, 4, 11205-11214	3.9	19	
76	Atomic layer deposition of zirconium dioxide from zirconium tetrachloride and ozone. <i>Thin Solid Films</i> , <b>2015</b> , 589, 597-604	2.2	18	
75	Low-Temperature Atomic Layer Deposition of Low-Resistivity Copper Thin Films Using Cu(dmap)2 and Tertiary Butyl Hydrazine. <i>Chemistry of Materials</i> , <b>2017</b> , 29, 6502-6510	9.6	18	
74	Atomic layer deposition of ytterbium oxide using -diketonate and ozone precursors. <i>Applied Surface Science</i> , <b>2009</b> , 256, 847-851	6.7	18	
73	Low-temperature atomic layer deposition of copper(II) oxide thin films. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , <b>2016</b> , 34, 01A109	2.9	18	
72	Tracing grog and pots to reveal Neolithic Corded Ware Culture contacts in the Baltic Sea region (SEM-EDS, PIXE). <i>Journal of Archaeological Science</i> , <b>2018</b> , 91, 77-91	2.9	17	
71	Influence of temperature-induced copper diffusion on degradation of selective chromium oxy-nitride solar absorber coatings. <i>Solar Energy Materials and Solar Cells</i> , <b>2016</b> , 145, 323-332	6.4	17	
70	Bismuth iron oxide thin films using atomic layer deposition of alternating bismuth oxide and iron oxide layers. <i>Thin Solid Films</i> , <b>2016</b> , 611, 78-87	2.2	16	
69	Rhenium Metal and Rhenium Nitride Thin Films Grown by Atomic Layer Deposition. <i>Angewandte Chemie - International Edition</i> , <b>2018</b> , 57, 14538-14542	16.4	16	

68	Atomic Layer Deposition of Molybdenum and Tungsten Oxide Thin Films Using Heteroleptic Imido-Amidinato Precursors: Process Development, Film Characterization, and Gas Sensing Properties. <i>Chemistry of Materials</i> , <b>2018</b> , 30, 8690-8701	9.6	16
67	Charge carrier dynamics in tantalum oxide overlayered and tantalum doped hematite photoanodes. <i>Journal of Materials Chemistry A</i> , <b>2019</b> , 7, 3206-3215	13	15
66	Inert ambient annealing effect on MANOS capacitor memory characteristics. <i>Nanotechnology</i> , <b>2015</b> , 26, 134004	3.4	15
65	Deposition of impurity metals during campaigns with the JET ITER-like Wall. <i>Nuclear Materials and Energy</i> , <b>2019</b> , 19, 218-224	2.1	14
64	Nanoscale lattice strains in self-ion implanted tungsten. <i>Acta Materialia</i> , <b>2020</b> , 195, 219-228	8.4	14
63	Potential gold(I) precursors evaluated for atomic layer deposition. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , <b>2017</b> , 35, 01B112	2.9	13
62	Optical characteristics of virgin and proton-irradiated ceramics of magnesium aluminate spinel. <i>Optical Materials</i> , <b>2019</b> , 96, 109308	3.3	13
61	Observation of Transient and Asymptotic Driven Structural States of Tungsten Exposed to Radiation. <i>Physical Review Letters</i> , <b>2020</b> , 125, 225503	7.4	13
60	Effect of interstitial carbon on the evolution of early-stage irradiation damage in equi-atomic FeMnNiCoCr high-entropy alloys. <i>Journal of Applied Physics</i> , <b>2020</b> , 127, 025103	2.5	13
59	Instability of the Sb vacancy in GaSb. <i>Physical Review B</i> , <b>2017</b> , 95,	3.3	12
58	(Et3Si)2Se as a precursor for atomic layer deposition: growth analysis of thermoelectric Bi2Se3. Journal of Materials Chemistry C, <b>2015</b> , 3, 4820-4828	7.1	12
57	Preparation of Lithium Containing Oxides by the Solid State Reaction of Atomic Layer Deposited Thin Films. <i>Chemistry of Materials</i> , <b>2017</b> , 29, 998-1005	9.6	11
56	Preparation and bioactive properties of nanocrystalline hydroxyapatite thin films obtained by conversion of atomic layer deposited calcium carbonate. <i>Biointerphases</i> , <b>2014</b> , 9, 031008	1.8	11
55	Modified deformation behaviour of self-ion irradiated tungsten: A combined nano-indentation, HR-EBSD and crystal plasticity study. <i>International Journal of Plasticity</i> , <b>2020</b> , 135, 102817	7.6	11
54	Hydrogen isotope exchange in tungsten during annealing in hydrogen atmosphere. <i>Nuclear Fusion</i> , <b>2019</b> , 59, 026016	3.3	11
53	Crystalline tungsten sulfide thin films by atomic layer deposition and mild annealing. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , <b>2019</b> , 37, 020921	2.9	10
52	Atomic layer deposition of aluminum oxide on modified steel substrates. <i>Surface and Coatings Technology</i> , <b>2016</b> , 304, 1-8	4.4	10
51	Intercalation of Lithium Ions from Gaseous Precursors into EMnO2 Thin Films Deposited by Atomic Layer Deposition. <i>Journal of Physical Chemistry C</i> , <b>2019</b> , 123, 15802-15814	3.8	9

## (2016-2018)

50	Effect of Au ion beam on structural, surface, optical and electrical properties of ZnO thin films prepared by RF sputtering. <i>Ceramics International</i> , <b>2018</b> , 44, 16464-16469	5.1	9
49	As2S3 thin films deposited by atomic layer deposition. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , <b>2017</b> , 35, 01B114	2.9	8
48	Atomic Layer Deposition of Intermetallic Co3Sn2 and Ni3Sn2 Thin Films. <i>Advanced Materials Interfaces</i> , <b>2019</b> , 6, 1801291	4.6	8
47	(Invited) Photo-Assisted ALD: Process Development and Application Perspectives. <i>ECS Transactions</i> , <b>2017</b> , 80, 49-60	1	7
46	Atomic layer deposition of lanthanum oxide with heteroleptic cyclopentadienyl-amidinate lanthanum precursor - Effect of the oxygen source on the film growth and properties. <i>Thin Solid Films</i> , <b>2018</b> , 660, 199-206	2.2	7
45	Comparative study of deuterium retention in irradiated Eurofer and Fettr from a new ion implantation materials facility. <i>Nuclear Fusion</i> , <b>2020</b> , 60, 016024	3.3	7
44	Atomic Layer Deposition of PbS Thin Films at Low Temperatures. Chemistry of Materials, 2020, 32, 8216	-8)262.8	7
43	Enhancement of vacancy diffusion by C and N interstitials in the equiatomic FeMnNiCoCr high entropy alloy. <i>Acta Materialia</i> , <b>2021</b> , 215, 117093	8.4	7
42	Proton induced gamma-ray production cross sections and thick-target yields for boron, nitrogen and silicon. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>2016</b> , 378, 25-30	1.2	6
41	Understanding the Stabilizing Effects of Nanoscale Metal Oxide and Li-Metal Oxide Coatings on Lithium-Ion Battery Positive Electrode Materials. <i>ACS Applied Materials &amp; ACS Applied Materials</i> (2011), 13, 4277	13 <sup>2</sup> - <del>4</del> 27	96
40	Studies on Li3AlF6 thin film deposition utilizing conversion reactions of thin films. <i>Thin Solid Films</i> , <b>2017</b> , 636, 26-33	2.2	5
39	Studies on solid state reactions of atomic layer deposited thin films of lithium carbonate with hafnia and zirconia. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , <b>2019</b> , 37, 020929	2.9	5
38	Selective etching of focused gallium ion beam implanted regions from silicon as a nanofabrication method. <i>Nanotechnology</i> , <b>2015</b> , 26, 265304	3.4	5
37	Nickel Germanide Thin Films by Atomic Layer Deposition. <i>Chemistry of Materials</i> , <b>2019</b> , 31, 5314-5319	9.6	5
36	Atomic Layer Deposition of TiO2 and ZrO2 Thin Films Using Heteroleptic Guanidinate Precursors. <i>Chemical Vapor Deposition</i> , <b>2014</b> , 20, 209-216		5
35	Stopping cross sections of atomic layer deposited Al2O3 and Ta2O5 and of Si3N4 for 12C, 16O, 35Cl, 79Br and 127I ions. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>2013</b> , 300, 1-5	1.2	5
34	Characterising Ion-Irradiated FeCr: Hardness, Thermal Diffusivity and Lattice Strain. <i>Acta Materialia</i> , <b>2020</b> , 201, 535-546	8.4	5
33	External beam IBA set-up with large-area thin Si3N4 window. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>2016</b> , 380, 11-14	1.2	5

32	Photoassisted atomic layer deposition of oxides employing alkoxides as single-source precursors. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2019, 37, 060911	2.9	5
31	Atomic Layer Deposition of Nickel Nitride Thin Films using NiCl2(TMPDA) and Tert-Butylhydrazine as Precursors. <i>Physica Status Solidi (A) Applications and Materials Science</i> , <b>2019</b> , 216, 1900058	1.6	4
30	Charge and current hysteresis in dysprosium-doped zirconium oxide thin films. <i>Microelectronic Engineering</i> , <b>2015</b> , 147, 55-58	2.5	3
29	Silicon oxide-niobium oxide mixture films and nanolaminates grown by atomic layer deposition from niobium pentaethoxide and hexakis(ethylamino) disilane. <i>Nanotechnology</i> , <b>2020</b> , 31, 195713	3.4	3
28	Atomic Layer Deposition of Zirconium Dioxide from Zirconium Tetraiodide and Ozone. <i>ECS Journal of Solid State Science and Technology</i> , <b>2018</b> , 7, P1-P8	2	3
27	Spin-glass magnetism of surface rich Au cluster film. <i>Applied Physics Letters</i> , <b>2011</b> , 99, 022503	3.4	3
26	Comparative study of deuterium retention and vacancy content of self-ion irradiated tungsten. Journal of Nuclear Materials, <b>2021</b> , 153373	3.3	3
25	Ionic conductivity in LixTaOy thin films grown by atomic layer deposition. <i>Electrochimica Acta</i> , <b>2020</b> , 361, 137019	6.7	3
24	Highly Material Selective and Self-Aligned Photo-assisted Atomic Layer Deposition of Copper on Oxide Materials. <i>Advanced Materials Interfaces</i> , <b>2021</b> , 8, 2100014	4.6	3
23	Toward epitaxial ternary oxide multilayer device stacks by atomic layer deposition. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , <b>2019</b> , 37, 020602	2.9	3
22	Comparative study on the use of novel heteroleptic cyclopentadienyl-based zirconium precursors with H2O and O3 for atomic layer deposition of ZrO2. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , <b>2019</b> , 37, 020912	2.9	2
21	Magnetic properties and resistive switching in mixture films and nanolaminates consisting of iron and silicon oxides grown by atomic layer deposition. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , <b>2020</b> , 38, 042405	2.9	2
20	Alkylsilyl compounds as enablers of atomic layer deposition: analysis of (Et3Si)3As through the GaAs process. <i>Journal of Materials Chemistry C</i> , <b>2016</b> , 4, 449-454	7.1	2
19	Rhenium Metal and Rhenium Nitride Thin Films Grown by Atomic Layer Deposition. <i>Angewandte Chemie</i> , <b>2018</b> , 130, 14746-14750	3.6	2
18	Atomic Layer Deposition of Zinc Glutarate Thin Films. <i>Advanced Materials Interfaces</i> , <b>2017</b> , 4, 1700512	4.6	2
17	VOLUMES OF WORTH <b>D</b> ELIMITING THE SAMPLE SIZE FOR RADIOCARBON DATING OF PARCHMENT. <i>Radiocarbon</i> , <b>2021</b> , 63, 105-120	4.6	2
16	Atomic layer deposition of TbF3 thin films. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , <b>2021</b> , 39, 022404	2.9	2
15	Thermal diffusivity recovery and defect annealing kinetics of self-ion implanted tungsten probed by insitu Transient Grating Spectroscopy. <i>Acta Materialia</i> , <b>2022</b> , 117926	8.4	2

#### LIST OF PUBLICATIONS

Hydrogen isotope exchange mechanism in tungsten studied by ERDA. Physica Scripta, 2020, T171, 01405£6 7 14 Two-step implantation of gold into graphene. 2D Materials, 2022, 9, 025011 13 5.9 Observed and Modeled Black Carbon Deposition and Sources in the Western Russian Arctic 12 10.3 1 1800-2014. Environmental Science & Environmental Scien MANOS performance dependence on ALD Al2O3 oxidation source. Microelectronic Engineering, 11 2.5 **2016**, 159, 127-131 Atomic layer deposition of cobalt(II) oxide thin films from Co(BTSA)2(THF) and H2O. Journal of 10 2.9 1 Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2019, 37, 010908 Charge state optimisation for beryllium accelerator mass spectrometry. Nuclear Instruments & 1.2 9 Methods in Physics Research B, 2020, 469, 33-36 Atomic layer deposition of GdF3 thin films. Journal of Vacuum Science and Technology A: Vacuum, 8 2.9 O Surfaces and Films, **2022**, 40, 022402 In-situ plasma treatment of Cu surfaces for reducing the generation of vacuum arc breakdowns. 2.5 Journal of Applied Physics, **2021**, 130, 143302 New perspectives on collision cascade damage in self-ion irradiated tungsten from HR-EBSD and 6 O 3.3 ECCI. Journal of Nuclear Materials, 2021, 554, 153074 High-fidelity patterning of AlN and ScAlN thin films with wet chemical etching. Materialia, 2022, 22, 101403 5 Laser induced breakdown spectroscopy for hydrogen detection in molybdenum at atmospheric 1.7 O pressure mixtures of argon and nitrogen. Fusion Engineering and Design, 2022, 179, 113131 Highly conductive and stable CoS thin films by atomic layer deposition: from process development and film characterization to selective and epitaxial growth. Dalton Transactions, **2021**, 50, 13264-13275  $^{4\cdot3}$ Molecular Layer Deposition of Thermally Stable Polybenzimidazole-Like Thin Films and 4.6 Nanostructures. Advanced Materials Interfaces, 2200370 From lakes to ratios: 14C measurement process of the Finnish tree-ring research consortium. 1.2 Nuclear Instruments & Methods in Physics Research B, 2022, 519, 37-45